

**Notice of References Cited**

Application/Control No.

09/207,546

Applicant(s)/Patent Under  
Reexamination  
DEGENDT ET AL.

Examiner

Shamim Ahmed

Art Unit

1746

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*		Document Number	Date	Name	Classification	
		Country Code-Number-Kind Code	MM-YYYY			
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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kern, Werner, "Hand Book of Semiconductor Wafer Cleaning Technology", 1993,p. 599-601.
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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